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Atty. Docket No.	Serial No.
<b>4105-22</b>	<b>10/658,751</b>
Applicant	
<b>CHO et al.</b>	
Filing Date	TC/A.U.
<b>September 10, 2003</b>	<b>2627</b>

**PATENT & TRADEMARK OFFICE**

## **U.S. PATENT DOCUMENTS**

## **FOREIGN PATENT DOCUMENTS**

## **TRANSLATION**

DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	YES	NO
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Cho et al, "Tbit/inch<sup>2</sup> ferroelectric data storage based on scanning nonlinear dielectric microscopy", Applied Physics Letters, Vol. 81, No. 23, December 2, 2002, pages 4401-4403.

\*Examiner \_\_\_\_\_ Date Considered \_\_\_\_\_

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<b>INFORMATION DISCLOSURE CITATION</b>		ATTY. DOCKET NO. <b>4105-22</b>	SERIAL NO. <b>10/658,751</b>
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\*Examiner

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	Cho et al, "Scanning nonlinear dielectric microscopy with nanometer resolution", Journal of European Ceramic Society 21 (2001) 2131-2134.
	Cho et al., "Nano domain engineering using scanning nonlinear dielectric microscopy, October 29, 2001, IEE-NANO 2001, pages 352-357.

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